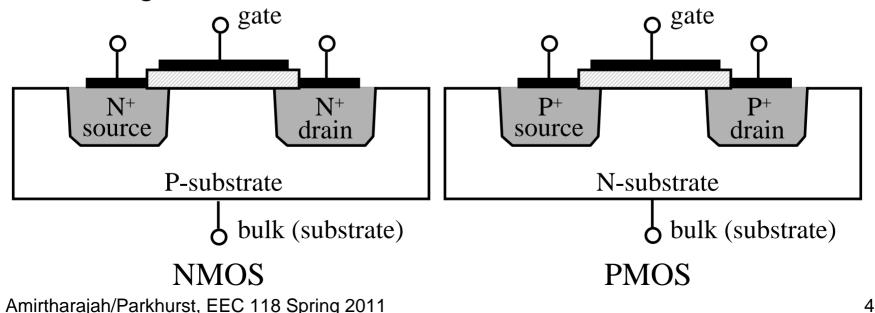
EEC 118 Lecture #2: MOSFET Structure and Basic Operation

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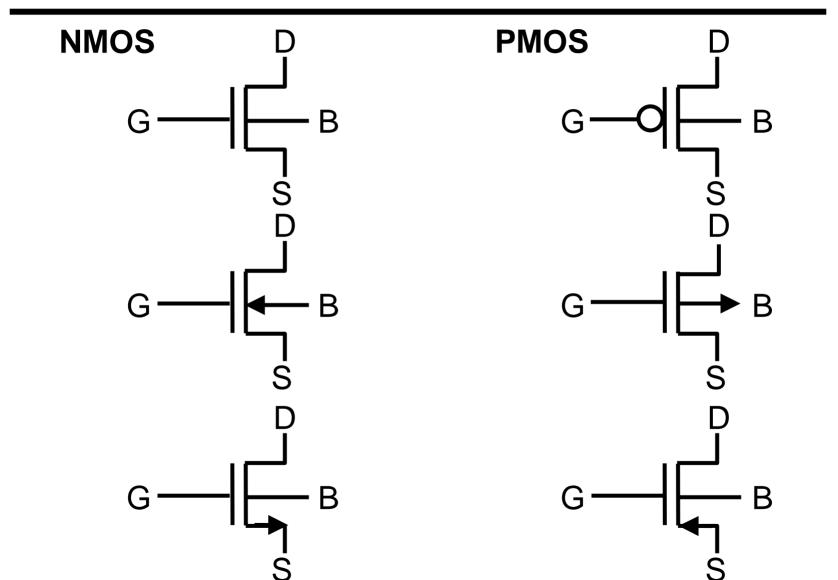
Outline

- Finish Lecture 1 Slides
- Switch Example
- MOSFET Structure
- MOSFET Regimes of Operation
- Scaling
- Parasitic Capacitances

- Rabaey Ch. 3 (Kang & Leblebici Ch. 3)
- Two transistor types (analogous to bipolar NPN, PNP)
 - NMOS: p-type substrate, n⁺ source/drain, electrons are charge carriers
 - PMOS: n-type substrate, p⁺ source/drain, holes are charge carriers



MOS Transistor Symbols



Note on MOS Transistor Symbols

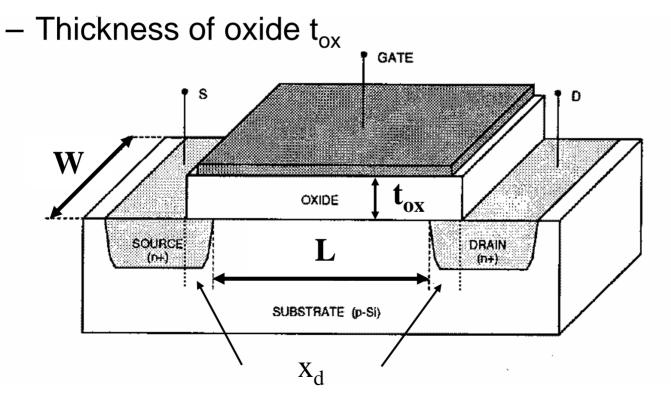
- All symbols appear in literature
 - Symbols with arrows are conventional in analog papers
 - PMOS with a bubble on the gate is conventional in digital circuits papers
- Sometimes bulk terminal is ignored implicitly connected to supply:



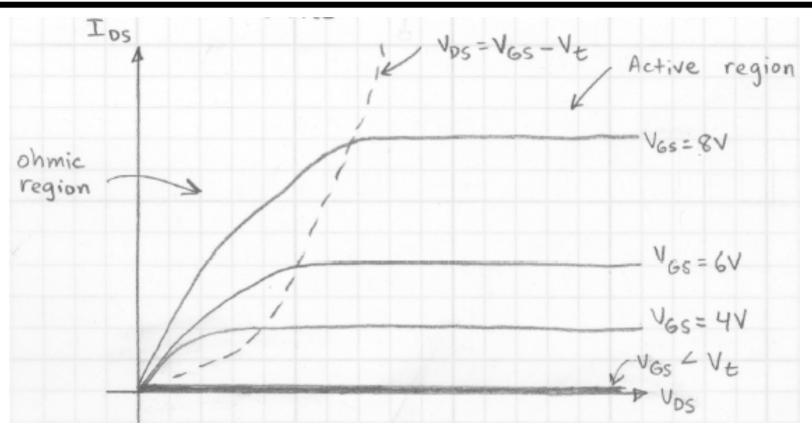
 Unlike physical bipolar devices, source and drain are usually symmetric

MOS Transistor Structure

- Important transistor physical characteristics
 - Channel length $L = L_D 2x_d$ (K&L L = Lgate 2L_D)
 - Channel width W



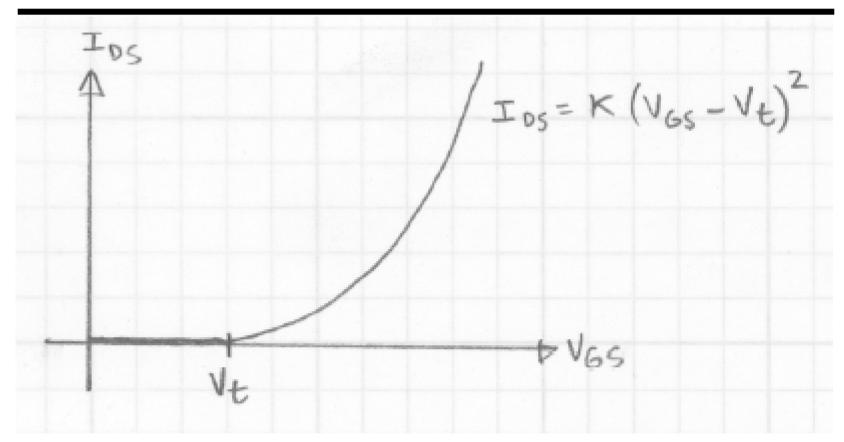
NMOS Transistor I-V Characteristics I



• I-V curve vaguely resembles bipolar transistor curves

- Quantitatively very different
- Turn-on voltage called <u>Threshold Voltage</u> V_T

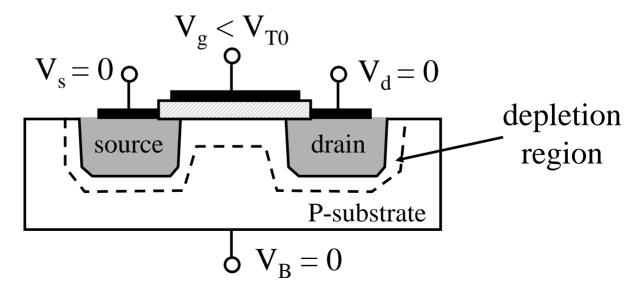
NMOS Transistor I-V Characteristics II



Drain current varies quadratically with gate-source voltage V_{GS} (in Saturation)

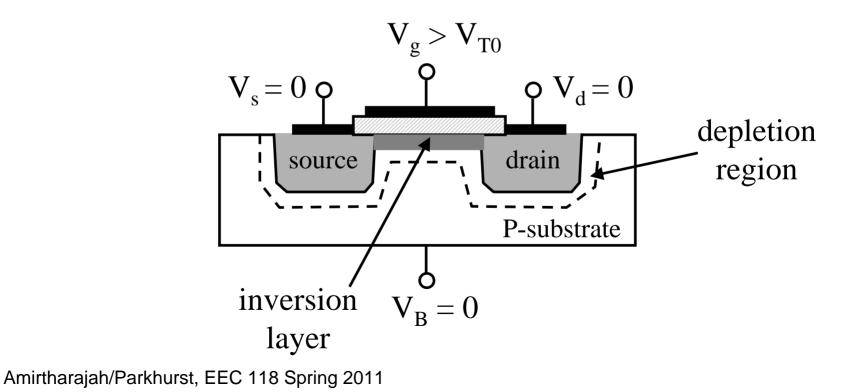
MOS Transistor Operation: Cutoff

- Simple case: $V_D = V_S = V_B = 0$
 - Operates as MOS capacitor (Cg = gate to channel)
 - Transistor in cutoff region
- When $V_{GS} < V_{T0}$, depletion region forms
 - No carriers in channel to connect S and D (Cutoff)



MOS Transistor Operation: Inversion

- When $V_{GS} > V_{T0}$, inversion layer forms
- Source and drain connected by conducting ntype layer (for NMOS)
 - Conducting p-type layer in PMOS



Threshold Voltage Components

- Four physical components of the threshold voltage
- 1. Work function difference between gate and channel (depends on metal or polysilicon gate): Φ_{GC}
- 2. Gate voltage to invert surface potential: $-2\Phi_F$
- 3. Gate voltage to offset depletion region charge: Q_B/C_{ox}
- 4. Gate voltage to offset fixed charges in the gate oxide and oxide-channel interface: Q_{ox}/C_{ox}

$$C_{ox} = \frac{\mathcal{E}_{ox}}{t_{ox}}$$

: gate oxide capacitance per unit area

• If V_{SB} = 0 (no substrate bias):

$$V_{T0} = \Phi_{GC} - 2\phi_F - \frac{Q_{B0}}{C_{ox}} - \frac{Q_{ox}}{C_{ox}} \quad (K\&L \ 3.20)$$

• If $V_{SB} \neq 0$ (non-zero substrate bias)

$$V_{T} = V_{T0} + \gamma \left(\sqrt{\left| -2\phi_{F} + V_{SB} \right|} - \sqrt{\left| 2\phi_{F} \right|} \right) \quad (3.19)$$

• Body effect (substrate-bias) coefficient:

$$\gamma = \frac{\sqrt{2qN_A \mathcal{E}_{Si}}}{C_{ox}}$$
(K&L 3.24)

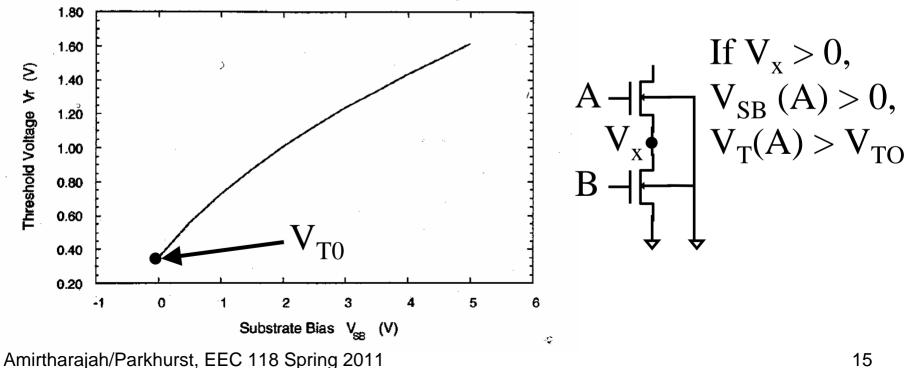
Threshold voltage increases as V_{SB} increases!

Threshold Voltage (NMOS vs. PMOS)

	NMOS	PMOS
Substrate Fermi potential	φ _F < 0	φ _F > 0
Depletion charge density	Q _B < 0	Q _B > 0
Substrate bias coefficient	γ > 0	γ < 0
Substrate bias voltage	V _{SB} > 0	V _{SB} < 0

Body Effect

- Body effect: Source-bulk voltage V_{SB} affects threshold voltage of transistor
 - Body normally connected to ground for NMOS, Vdd (Vcc) for PMOS
 - Raising source voltage increases V_T of transistor
 - Implications on circuit design: series stacks of devices



MOS Transistor Regions of Operation

- Three main regions of operation
- <u>Cutoff</u>: $V_{GS} < V_T$ No inversion layer formed, drain and source are isolated by depleted channel. $I_{DS} \approx 0$
- <u>Linear (Triode, Ohmic)</u>: $V_{GS} > V_T$, $V_{DS} < V_{GS} V_T$ Inversion layer connects drain and source. Current is almost linear with V_{DS} (like a resistor)
- <u>Saturation</u>: V_{GS} > V_T, V_{DS} ≥ V_{GS}-V_T
 Channel is "pinched-off". Current saturates (becomes independent of V_{DS}, to first order).

Saturation:
$$I_D = \frac{\mu C_{ox}}{2} \frac{W}{L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

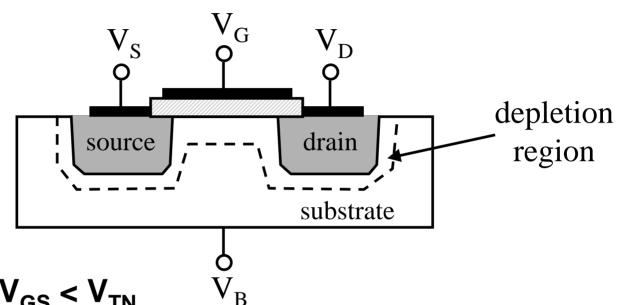
Linear (Triode, Ohmic):

$$I_D = \mu C_{ox} \frac{W}{L} \left(\left(V_{GS} - V_T \right) V_{DS} - \frac{V_{DS}^2}{2} \right)$$

Cutoff: $I_D \approx 0$

"Classical" MOSFET model, will discuss deep submicron modifications as necessary (Rabaey, Eqs. 3.25, 3.29)

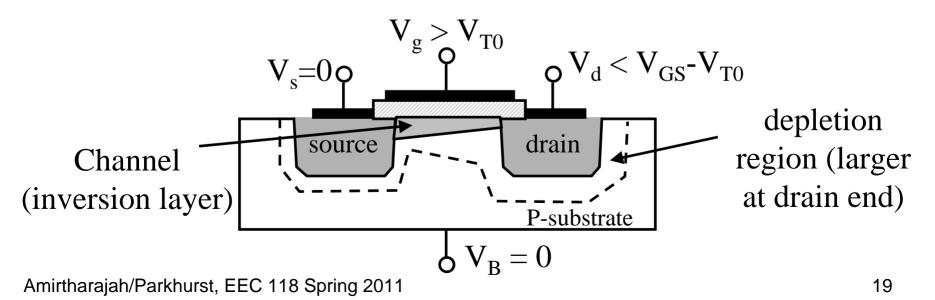
Cutoff Region



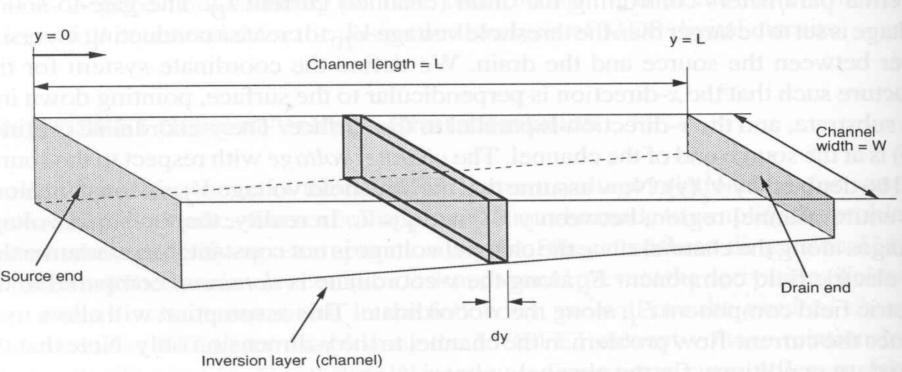
- For NMOS: $V_{GS} < V_{TN}$
- For PMOS: $V_{GS} > V_{TP}$
- Depletion region no inversion
- Current between drain and source is 0
 - Actually there is always some leakage (subthreshold) current

Linear Region

- When V_{GS}>V_T, an inversion layer forms between drain and source
- Current I_{DS} flows from drain to source (electrons travel from source to drain)
- Depth of channel depends on V between gate and channel
 - Drain end narrower due to larger drain voltage
 - Drain end depth reduces as V_{DS} is increased



Linear Region I/V Equation Derivation



- Gradual Channel Approximation:
 - Assume dominant electric field in y-direction
 - Current is constant along channel

Integrate differential voltage drop dV_c = I_DdR along y

• Valid for continuous channel from Source to Drain

$$I_{D} = \mu_{n} C_{ox} \frac{W}{L} \left[\left(V_{GS} - V_{T} \right) V_{DS} - \frac{1}{2} V_{DS}^{2} \right]$$

Device transconductance:

$$k_n = \mu_n C_{ox} \frac{W}{L}$$

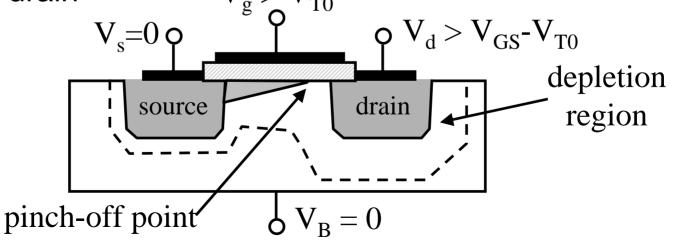
Process transconductance:
$$k_n' = \mu_n C_{ox}$$

$$I_D = k_n' \frac{W}{L} \left[\left(V_{GS} - V_T \right) V_{DS} - \frac{1}{2} V_{DS}^2 \right]$$

Saturation Region

• When $V_{DS} = V_{GS} - V_{T}$:

- No longer voltage drop of V_T from gate to substrate at drain Channel is "pinched off"
- If V_{DS} is further increased, no increase in current I_{DS}
 - As V_{DS} increased, pinch-off point moves closer to source
 - Channel between that point and drain is depleted
 - High electric field in depleted region accelerates electrons towards drain $V_g > V_{T0}$

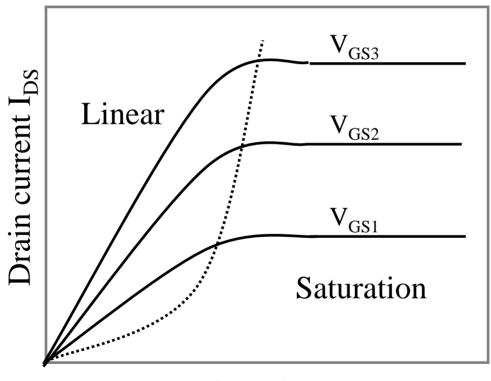


Saturation I/V Equation

- As drain voltage increases, channel remains pinched off
 - Channel voltage remains constant
 - Current saturates (no increase with increasing V_{DS})
- To get saturation current, use linear equation with $V_{DS} = V_{GS} V_T$

$$I_{D} = \frac{1}{2} \mu_{n} C_{ox} \frac{W}{L} (V_{GS} - V_{TN})^{2}$$

- I/V curve for ideal MOS device
- $V_{GS3} > V_{GS2} > V_{GS1}$



Drain voltage V_{DS}

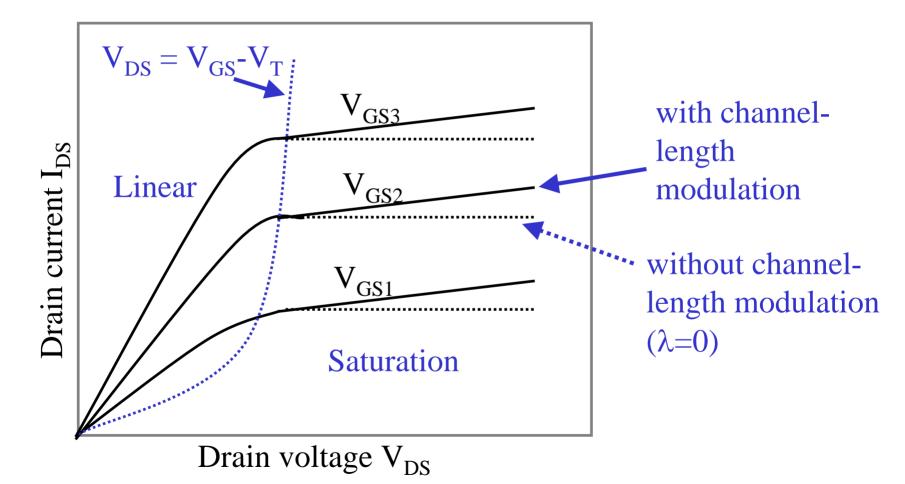
- In saturation, pinch-off point moves
 - As V_{DS} is increased, pinch-off point moves closer to source
 - Effective channel length becomes shorter
 - Current increases due to shorter channel

$$\dot{L} = L - \Delta L$$

$$I_{D} = \frac{1}{2} \mu_{n} C_{ox} \frac{W}{L} (V_{GS} - V_{TN})^{2} (1 + \lambda V_{DS})$$

 λ = channel length modulation coefficient

I/V curve for non-ideal NMOS device:



MOS I/V Equations Summary

$$\begin{array}{ll} \textbf{Cutoff} & V_{GS} < V_{TN} \\ & V_{GS} > V_{TP} \end{array} \Longrightarrow I_D = 0 \end{array}$$

Linear

$$V_{GS} \ge V_{TN}, \quad V_{DS} < V_{GS} - V_{TN} \Longrightarrow I_D = \mu C_{ox} \frac{W}{L} \Big[(V_{GS} - V_T) V_{DS} - \frac{1}{2} V_{DS}^2 \Big]$$

$$V_{GS} \le V_{TP}, \quad V_{DS} > V_{GS} - V_{TP} \Longrightarrow I_D = \mu C_{ox} \frac{W}{L} \Big[(V_{GS} - V_T) V_{DS} - \frac{1}{2} V_{DS}^2 \Big]$$

Saturation

$$V_{GS} \ge V_{TN}, \quad V_{DS} \ge V_{GS} - V_{TN} \Longrightarrow I_D = \frac{1}{2} \mu C_{ox} \frac{W}{L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

$$V_{GS} \le V_{TP}, \quad V_{DS} \le V_{GS} - V_{TP}$$

Note: if $V_{SB} \neq 0$, need to recalculate V_T from V_{T0}

A Fourth Region: Subthreshold

Subthreshold:
$$I_D = I_S e^{\frac{V_{GS}}{n^{kT/q}}} \left(1 - e^{-\frac{V_{DS}}{kT/q}}\right)$$

- Sometimes called "weak inversion" region
- When V_{GS} near V_T, drain current has an exponential dependence on gate to source voltage
 - Similar to a bipolar device
- Not typically used in digital circuits
 - Sometimes used in very low power digital applications
 - Often used in low power analog circuits, e.g. quartz watches

MOSFET Scaling Effects

- Rabaey Section 3.5 (Kang & Leblebici Section 3.5)
- Scaling provides enormous advantages
 - Scale linear dimension (channel length) by factor S > 1
 - Better area density, yield, performance

Two types of scaling

- Constant field scaling (full scaling)

•
$$A' = A/S^2$$
; $L' = L/S$; $W' = W/S$; $I_D' = I_D/S$; $P' = P/S^2$; $V_{dd}' = V_{dd}/S$

• Power Density P'/A' = stays the same $_{Change}$ these two

- Constant voltage scaling

- $A' = A/S^2$; L' = L/S; W' = W/S; $I_D' = I_D^*S$; $P' = P^*S$; $V_{dd}' = V_{dd}$
- Power Density P'/A' = $S_{\star}^{3*}P$ (Reliability issue)

Amirtharajah/Parkhurst, EEC 118 Spring 2011

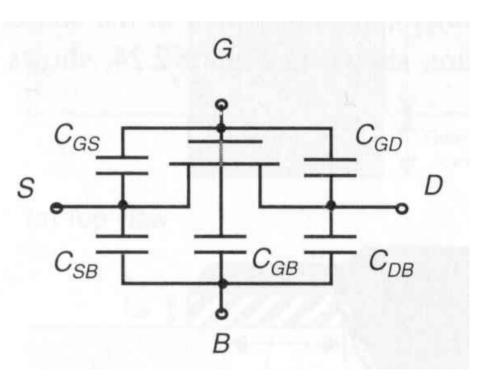
This changed as well

Short Channel Effects

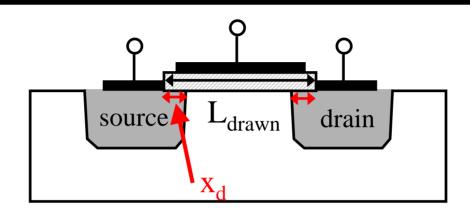
- As geometries are scaled down
 - $-V_T$ (effective) goes lower
 - Effective channel length decreases
 - Sub-threshold Ids occurs
 - Current goes from drain to source while Vgs < Vt
 - Tox is scaled which can cause reliability problems
 - Can't handle large Vg without hot electron effects
 - Changes the Vt when carriers imbed themselves in the oxide
 - Interconnects scale
 - Electromigration and ESD become issues

MOSFET Capacitances

- Rabaey Section 3.3 (Kang & Leblebici Section 3.6)
- Oxide Capacitance
 - Gate to Source overlap
 - Gate to Drain overlap
 - Gate to Channel
- Junction Capacitance
 - Source to Bulk junction
 - Drain to Bulk junction



Oxide Capacitances: Overlap



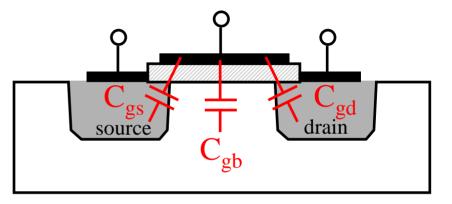
- Overlap capacitances
 - Gate electrode overlaps source and drain regions
 - x_d is overlap length on each side of channel
 - $L_{eff} = L_{drawn} 2x_d$ (effective channel length)

- Overlap capacitance:

$$C_{GSO} = C_{GDO} = C_{ox}Wx_d$$
 Assume x_d equal on both sides

Total Oxide Capacitance

- Total capacitance consists of 2 components
 - Overlap capacitance
 - Channel capacitance



- Cutoff:
 - No channel connecting to source or drain

$$-C_{GS} = C_{GD} = C_{ox}Wx_{d}$$

$$- C_{GB} = C_{ox}WL_{eff}$$

- Total Gate Capacitance = $C_G = C_{ox}WL$

• Linear mode

- Channel spans from source to drain
- Channel Capacitance split equally between S and D

$$C_{GS} = \frac{1}{2}C_{ox}WL_{eff} C_{GD} = \frac{1}{2}C_{ox}WL_{eff} C_{GB} = 0$$

– Total Gate capacitance $C_G = C_{ox}WL$

Saturation regime

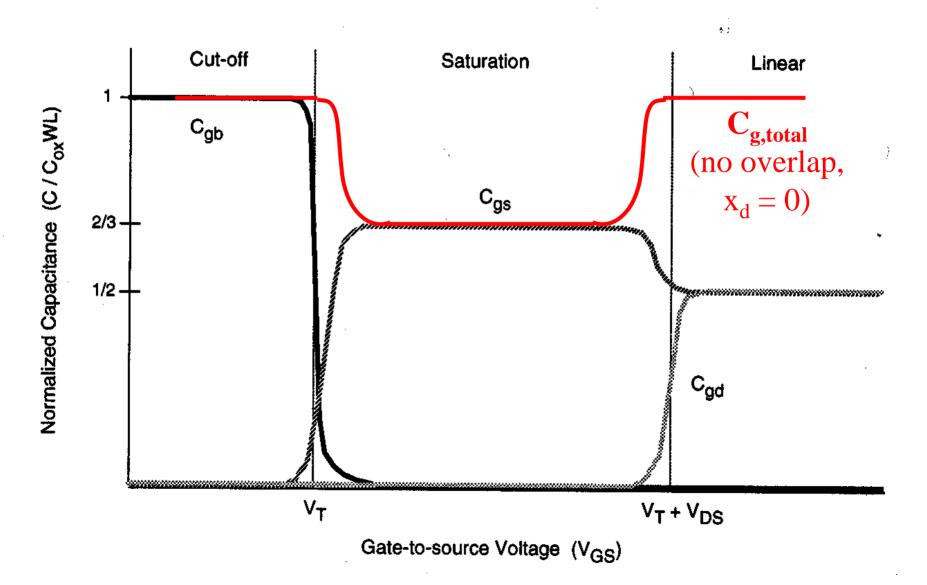
- Channel is pinched off: Channel Capacitance --

$$C_{GD} = W x_d C_{ox} \quad C_{GS} = \frac{2}{3} C_{ox} W L_{eff} + C_{OX} W x_d \quad C_{GB} = 0$$

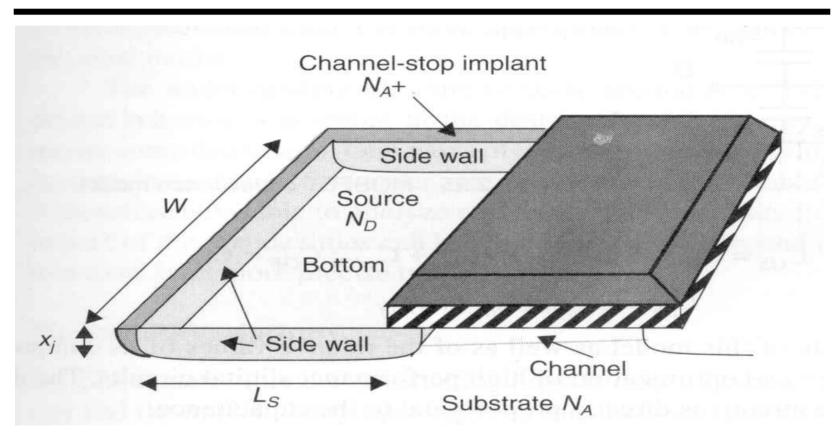
- Total Gate capacitance:

$$C_G = 2/3 C_{ox}WL_{eff} + 2x_dWC_{OX}$$

Oxide Capacitances: Channel



Junction Capacitance



Reverse-biased P-N junctions! Capacitance depends on reverse-bias voltage.

Junction Capacitance

For a P-N junction:
$$C_j = \frac{A}{2} \sqrt{\frac{2q\varepsilon}{V_0 - V} \frac{N_d N_a}{N_d + N_a}}$$
If V=0, cap/area = $C_{j0} = \sqrt{\frac{q\varepsilon_{Si}}{2V_0} \frac{N_d N_a}{N_d + N_a}}$ General form: $C_j = \frac{AC_{j0}}{\left(1 - \frac{V}{V_0}\right)^m}$

m = grading coefficient (0.5 for abrupt junctions) (0.3 for graded junctions)

- Junction with substrate
 - Bottom area = W * L_S (length of drain/source)
 - Total cap = C_i
- Junction with sidewalls
 - "Channel-stop implant"
 - Perimeter = $2L_S + W$
 - Area = P * X_i
 - Total cap = C_{jsw}
- Total junction cap C = C_j + C_{jsw}

Junction Capacitance

- Voltage Equivalence Factor
 - Creates an average capacitance value for a voltage transition, defined as $\Delta Q/\Delta V$

$$C_{eq} = \frac{-AC_{j0}V_0}{(V_2 - V_1)(1 - m)} \left(\left(1 - \frac{V_2}{V_0}\right)^{1 - m} - \left(1 - \frac{V_1}{V_0}\right)^{1 - m} \right) = AK_{eq}C_{j0}$$

 $K_{eq} = \frac{-2\sqrt{V_0}}{(V_2 - V_1)} \left(\sqrt{V_0 - V_2} - \sqrt{V_0 - V_1} \right)$ (abrupt junction only)

$$C_{db} = AK_{eq}C_{j0} + PX_{j}K_{eqsw}C_{jsw0}$$

- Consider the following NMOS device
 - Substrate doping: $N_A = 10^{15} \text{ cm}^{-3}$
 - Source/drain doping: $N_D = 2 \times 10^{20} \text{ cm}^{-3}$
 - Channel-stop doping: 10X substrate doping
 - Drain length $L_D = 1$ um
 - Transistor W = 10um
 - Junction depth Xj = 0.5um, abrupt junction

• Find capacitance of drain-bulk junction when drain voltage = 3V

- Inverter Characteristics
 - Transfer functions, noise margins, resistive and nonlinear loads
- CMOS Inverters